Dear Reviewer 3

**JoVE59376**

“Accumulation and Analysis Methods of Copper Ion in Copper Sulfate Plating Solution”

Toshiaki Koga, Yoshitaro Sakata, and Nao Terasaki

We thank reviewer for careful reading our manuscript. We appreciate that you are interested in our report.

We look forward to a publication of our manuscript in Journal of Visualized Experiments.

Sincerely

Toshiaki Koga